

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: NAKATA, Yoshihiro et al.

Group Art Unit: 1771

Serial No.: 10/807,174

Examiner: Hai VO

Filed: March 24, 2004

P.T.O. Confirmation No.: 4205

FOR: SILICON-BASED COMPOSITION, LOW DIELECTRIC CONSTANT FILM,

SEMICONDUCTOR DEVICE, AND METHOD FOR PRODUCING LOW

DIELECTRIC CONSTANT FILM

AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

MAILSTOP RCE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

October 29, 2007

Sir:

In response to the Office Action dated **June 4, 2007**, please amend the above-identified application as follows. A Request for Continued Examination (RCE) and a Petition for Extension of time are concurrently filed herewith.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.